

ABSTRACT

Microelectricalmechanical systems (MEMS) manufactured on a microscopic scale using integrated circuit techniques may be used to measure a variety of parameters using electrical signals generated by the movement of small beams. Inertial noise may be canceled by the duplication of the beam structure for sensing of the acceleration to be subtracted from a similar beam structure used to measure the parameter of interest.

5006903_1.Doc

Docket No. 110003.97346